Special Issue

Condition Monitoring and Their Applications in Industry

Message from the Guest Editors

Critical assets such as machinery and structures are essential for economic activities across most sectors. Condition monitoring of these critical assets is essential for optimal usage. Such monitoring processes involve detecting faults at an early stage, diagnosing the fault source and monitoring and predicting the fault progression. Achieving these objectives successfully for both machinery and structures requires use of a range of data analysis techniques that are typically developed for the specific application. While numerous theoretical data analysis, machine learning and signal processing techniques have evolved, this Special Edition presents only industrial-application-based papers in which the latest condition monitoring techniques are applied to machinery and structures. Keywords:

- Condition monitoring
- Machinery
- Structures
- Diagnosis
- Prognosis

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Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

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